

Contents

1	Introduction	1
1.1	Material Properties	2
1.2	Electronics Properties	3
1.3	Optical Properties	5
1.4	Light Emitters	6
1.4.1	Heterojunction Light-Emitting Diodes	6
1.4.2	Homojunction Light-Emitting Diodes	7
1.5	Light Detectors	8
2	Optimisation of PLD Parameters	9
2.1	Introduction	10
2.2	Temperature Optimisation	10
2.2.1	Experimental Details	10
2.2.2	Results and Discussion	10
2.2.3	Conclusion	16
2.3	Pressure Optimisation	17
2.3.1	Results and Discussion	17
2.3.2	Conclusion	23
2.4	Hydrogen Ion Implantation	24
2.4.1	Results and Discussion	24
2.4.2	Conclusion	30
3	Implantation Studies	31
3.1	Introduction	32
3.2	Conventional Ion Implantation Studies	32
3.2.1	Deposition of ZnO	32
3.2.2	Lithium Implantation Studies	32
3.2.3	Phosphorus Implantation Studies	44
3.3	Plasma Immersion Ion Implantation Studies	54
3.3.1	Deposition of ZnO	54
3.3.2	Phosphorus Implantation Studies	54
3.3.3	Nitrogen Implantation Studies	61

4	Fabrication of Optoelectronics Devices	67
4.1	Introduction	68
4.2	Fabrication Steps	68
4.3	Heterojunction Devices	69
4.3.1	p-ZnO/n-Si	69
4.3.2	p-ZnO/p-Si Detector	70
4.4	Homojunction Devices	71
4.4.1	p-ZnO/n-ZnO Homojunction LED	71
4.5	Conclusion	73
5	Summary and Future Works	75
	References	77

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